

AMENDMENTS TO THE SPECIFICATION:

At page 1, please amend the title appearing at lines 3-6 as follows:

C1
METHOD OF MANUFACTURING ~~ELECTRONIC DEVICE,~~
~~ELECTRON SOURCE SUBSTRATE, AND IMAGE FORMING APPARATUS, AND~~
~~APPARATUS FOR MANUFACTURING ELECTRONIC DEVICE AND ELECTRON~~
~~SOURCE SUBSTRATE/~~ELECTRON-EMITTING DEVICE USING INK-JET
DISCHARGE DEVICE

Please amend the Abstract appearing at page 48, lines 2-14 as follows:

C2
An ~~electronic~~ electron-emitting device manufacturing ~~apparatus~~ includes
method comprising a gas removal means for step of removing a gas dissolved in a liquid
containing ~~the~~ a formation material of ~~a member constituting an electronic device an~~
electroconductive film in which an electron emitting area is to be formed, a temperature
adjusting step of adjusting a temperature of the liquid from which the gas is removed, and
a droplet discharge ~~means for step of discharging droplets of which the temperature is~~
adjusted the liquid by droplet discharge means in an ink jet manner, and a means for while
controlling ~~the~~ relative positions of the droplet discharge means and a substrate on which
the ~~electronic device~~ electroconductive film in which the electron-emitting area is to be
formed is formed. The droplets are thereby applied to a predetermined position on the

C2 substrate. ~~The gas removal means includes a closed vessel filled with membrane formed from a semi-transmitting film capable of transmitting a gas, and a vacuum unit for evacuating the closed vessel.~~
